PROCEEDINGS OF SPIE

Optifab 2017

Julie L. Bentley Sebastian Stoebenau Editors

16–20 October 2017 Rochester, New York, United States

Sponsored by SPIE

Cosponsored by The American Precision Optics Manufacturers Association (United States)

Published by SPIE

Volume 10448

Proceedings of SPIE 0277-786X, V. 10448

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Optifab 2017, edited by Julie L. Bentley, Sebastian Stoebenau, Proc. of SPIE Vol. 10448, 1044801 · © 2017 SPIE · CCC code: 0277-786X/17/\$18 · doi: 10.1117/12.2305130

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Please use the following format to cite material from these proceedings: Author(s), "Title of Paper," in *Optifab 2017*, edited by Julie L. Bentley, Sebastian Stoebenau, Proceedings of SPIE Vol. 10448 (SPIE, Bellingham, WA, 2017) Seven-digit Article CID Number.

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510613645

ISBN: 9781510613652 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA Telephone +1 360 676 3290 (Pacific Time)· Fax +1 360 647 1445

SPIE.org

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Printed in the United States of America.

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